Special Issue

Artificial Intelligence on MEMS/Microdevices/Microsysten

Message from the Guest Editors

This Special Issue will be focused on microelectromechanical systems (MEMS)/microdevices and systems with artificial intelligence (AI). Artificial intelligence (AI), through those devices and systems. makes it possible for machines to learn from experience, adjust to new inputs, and perform humanlike tasks. Making microstructures is being challenging task day by day. Therefore, in order to improve and optimize device and system performance, AI is a significant candidate that can mitigate the problem occurring in those devices and systems. This Special Issue seeks research papers and review articles that focus on novel methodological developments of Al on MEMs/microdevices and systems for various communication systems. We look forward to receiving vour submissions!

Guest Editors

Prof. Dr. Yeonwoo Lee

Department of Artificial Intelligence Engineering, Mokpo National University, Cheonggye-myeon, Muan-gun, Jeollanam-do, Republic of Korea

Prof. Dr. Bhanu Shrestha

Department of Electronic Engineering, Kwangwoon University, Bima Build. #525, 20 Kwangwoon-ro, Nowon-gu, Seoul 01897, Republic of Korea

Deadline for manuscript submissions

closed (15 April 2021)



Micromachines

an Open Access Journal by MDPI

Impact Factor 3.0 CiteScore 5.2 Indexed in PubMed



mdpi.com/si/59905

Micromachines
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland
Tel: +41 61 683 77 34
micromachines@mdpi.com

mdpi.com/journal/ micromachines





an Open Access Journal by MDPI

Impact Factor 3.0
CiteScore 5.2
Indexed in PubMed



About the Journal

Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

Editor-in-Chief

Prof. Dr. Ai-Qun Liu

- 1. Department of Electrical and Electronic Engineering, The Hong Kong Polytechnic University, Hong Kong, China
- 2. School of Electrical and Electronic Engineering, Nanyang Technological University, Singapore 639798, Singapore

Author Benefits

High Visibility:

indexed within Scopus, SCIE (Web of Science), PubMed, PMC, Ei Compendex, dblp, and other databases.

Journal Rank:

JCR - Q2 (Physics, Applied) / CiteScore - Q2 (Mechanical Engineering)

Rapid Publication:

manuscripts are peer-reviewed and a first decision is provided to authors approximately 17.7 days after submission; acceptance to publication is undertaken in 2.5 days (median values for papers published in this journal in the first half of 2024).

